

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Mitsushi FUJIKI**

Serial Number: **Not Yet Assigned**

Filed: **February 6, 2004**

Customer No.: 38834

For: **METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

February 6, 2004


Sir:

In compliance with 37 CFR 1.56, Applicant(s) call(s) to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,
WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP



Scott M. Daniels
Reg.: 32,562

Atty. Docket No.: 042068
1250 Connecticut Avenue, N.W., Suite 700
Washington, D.C. 20036
Tele: (202) 822-1100
Fax: (202) 822-1111
SMD/ll
Enclosures: PTO-1449; References (2)

INFORMATION DISCLOSURE STATEMENT PTO-1449	Attv. Docket No. 042068	Serial No. New Appln.
	Applicant(s): Mitsushi FUJIKI	
	Filing Date: February 6, 2004	Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
	AA					
	AB					
	AC					
	AD					

FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)
9-53188	02/25/97	Japan	Abstract & Discussed in the Spec.
AE			
AF			
AG			
AH			
AI			

OTHER DOCUMENTS

AJ	Jpn. J. Appl. Phys. Vol. 36 (1997) pp. L154-L157, Part 2, No. 2A, 1 February 1997 Takeshi OHWAKI et al., Preferred Orientation in Ti Films Sputter-Deposited on SiO ₂ Glass: The Role of Water Chemisorption on the Substrate
AK	
Examiner	Date Considered